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Sheet 1 of 1 NOV 2 7 2006

FORM 1449* INFORMATION DISCLOSURE STATEMENT	Docket Number: 14434.103USWO	Application Number: UNKNOWN	
IN AN APPLICATION .	Applicant: TAKEUCHI et al.		
(Use several sheets if necessary)	Filing Date: concurrent herewith	Group Art Unit: UNKNOWN	

		U.S	S. PATENT DOCUMENT	<u>'S</u>			
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING D. IF APPROPI	
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EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form for next communication to the Applicant.

*Sydstitute Disclosure Statement Form (PTO-1449)

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